

Patent Claims

What is claimed:

1. A damper for protecting a sensor of a gauge measuring the
5 pressure of a dry etch chamber, comprising:

a vacuum tube for connecting the gauge with the chamber; and

at least one plate for blocking the plasma of the chamber from
directly striking against the sensor, disposed at the inner wall of the
vacuum tube.

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2. The damper of Claim 1, wherein the at least one plate is a
stainless steel plate.

3. The damper of Claim 1, further comprising a reticular
15 structure disposed at the front end of the vacuum tube near the
chamber.

4. The damper of Claim 3, wherein the reticular structure is a
wire netting.

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5. A damper for protecting a sensor of a gauge measuring the
pressure of a dry etch chamber, comprising:

a vacuum tube for connecting the gauge with the chamber; and

two plates for blocking the plasma of the chamber from directly striking against the sensor, respectively and separately disposed at the upper inner wall and the lower inner wall of the vacuum tube.

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6. The damper of Claim 5, further comprising a reticular structure disposed at the front end of the vacuum tube near the chamber.